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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Ryo TAKAI et al.

Application No.: 10/073,593

Filed: February 12, 2002

For: EXPOSURE APPARATUS INCLUDING
INTERFEROMETER SYSTEM

)
: Examiner: M. A. Lyons
)
: Group Art Unit: 2877
)
: Confirmation No. 4328
)
: Allowed: February 27, 2004
): May 13, 2004

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

LETTER TRANSMITTING CORRECTED FORMAL DRAWINGS

Sir:

Transmitted herewith are three (3) formal drawing sheets, corrected Figure 13-15, to be substituted for the corresponding drawing sheet currently on file in the above-identified application.

Figures 13-15 incorporate the changes requested by Applicants in a Request for Approval of Drawings Change filed October 16, 2003, which were subsequently approved by the Examiner in the Notice of Allowability dated February 27, 2004.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,



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